

1792

1110-94326 PATENT



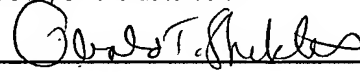
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

App. No. : 10/534,946
Applicant : YOKOYAMA et al.
Filed : 11 May 2005
Art Unit : 1792
Examiner : SONG, Mathew J.
Docket No. : 1110-94326
Customer No. : 24628
Title : SILICON WAFER, ITS
MANUFACTURING METHOD, AND ITS
MANUFACTURING APPARATUS

Confirmation No.: 3657

**CERTIFICATE OF MAILING BY
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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, on the date below.



9 April 2008
(Date)

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

The Office Action of January 10, 2008 has been carefully reviewed and the following amendments and remarks are made in response thereto: